

Electronic Patent Application Fee Transmittal

Application Number:	10506457			
Filing Date:	05-Jan-2005			
Title of Invention:	DEVICE AND METHOD FOR ANISOTROPIC PLASMA ETCHING OF A SUBSTRATE, A SILICON BODY IN PARTICULAR			
First Named Inventor/Applicant Name:	Franz Laermer			
Filer:	Gerard A. Messina/Tesha Ramos			
Attorney Docket Number:	10191/3935			
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U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1400	1400
Publ. Fee- early, voluntary, or normal	1504	1	300	300

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Total in USD (\$)				1700